



Low Temperature Dry Reforming of Methane over Plasmonic Ni Photocatalysts Under Visible Light Irradiation

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COMMUNICATION

Low Temperature Dry Reforming of Methane over Plasmonic Ni Photocatalysts Under Visible Light Irradiation

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Low temperature CO₂ conversion with CH₄ into syngas (dry reforming of methane, DRM) was achieved over plasmonic Ni/Al₂O₃ photocatalysts with high conversion of CO₂ (21%) and CH₄ (20%) using a fixed-bed flow reactor at 473 K. The formation rates of CO and H₂ were 1.87 and 1.20 mmol h⁻¹, respectively, and these values were over 47 times higher than that of the Ga₂O₃ photocatalyst previously reported by our group. To the best of our knowledge, this is the first report that the high formation rates of CO and H₂ were achieved at 473 K in the DRM reaction under visible light. Besides, the CO/H₂ ratio was successfully controlled by changing the CO₂/CH₄ ratio in the feed gas mixture.

Concentration of carbon dioxide (CO₂) in the atmosphere has been increasing year by year, and the CO₂ emissions are a serious problem because of its contribution to the climate change. To reduce the CO₂ emission amount, development of novel technologies for the chemical conversion of CO₂ are strongly-desired. Dry reforming of methane (DRM)^{1,2} is one of the promising technologies for the conversion of CO₂, where CO₂ reacts with abundantly available CH₄ gas to produce industrially important syngas (eq. 1).



Typically, the DRM reaction has to be operated at high temperature of 1073–1273 K to obtain high equilibrium conversion (eq. 1) because the reaction is highly endothermic. Furthermore, carbon deposition is also serious problem in many DRM reactions² although extensive research has been conducted in this field. To solve these problems, utilization of light energy is a potential method because the photocatalytic reaction occurs at low temperatures beyond the thermodynamic limit. Photocatalytic reaction between CO₂ and

CH₄ was firstly reported over ZrO₂, and the authors confirmed that the evolved CO derives from only CO₂ molecules introduced.^{3,4} The same group reported that MgO worked as a photocatalyst for the reaction between CO₂ and CH₄ under UV-light irradiation although H₂ was not observed.⁵ Our group firstly succeeded in the conversion of CO₂ and CH₄ into CO and H₂ using a Ga₂O₃ photocatalyst (photo-DRM) at mild temperatures around 473 K compared to the thermal DRM reaction condition.^{6,7} However, in that system, the photocatalytic activity is insufficient (CO: 1.1 μmol and H₂: 2.5 μmol after 3 h) even under UV light irradiation at 473 K.⁷ Recently, photocatalytic approach has been investigated extensively for the DRM reaction.^{8–15} In 2015, it was firstly proposed that a localized surface plasmon resonance (LSPR) by Au was effective for the activity enhancement of the DRM reaction at 773 K.⁸ Other group reported a black-TiO₂ photocatalyst for the DRM reaction, and the activity was improved under visible light in the temperature range of 623–1050 K.⁹ Recently, Ni based plasmonic photocatalysts were reported for photo-DRM at reaction temperatures over 673 K by several groups.^{10,11,14} In spite of the extensive research, the reaction temperature is still high, and photo-DRM at a mild reaction temperature around 473 K has not been achieved yet. In the present study, we investigated various photocatalysts and reaction conditions to obtain the high yield of CO and H₂ in the photo-DRM reaction under light irradiation at a mild reaction temperature of 473 K.

The metal-loaded photocatalysts were prepared by an impregnation method. The catalytic activity tests were carried out using a fixed-bed flow reactor as described in our previous study,^{16,17} and the sample was irradiated by a 300 W Xe lamp with or without a long-pass filter ($\lambda > 430$ nm, Fig. S1). Before the catalytic activity test, the sample was reduced by H₂ (10%)/Ar gas at 623 K (typically). Ni K-edge XAFS measurements were performed at BL12C of the Photon Factory (PF, Tsukuba, Japan). The experimental detail was shown in ESI.

First, effect of the metal loading on a Ga₂O₃ photocatalyst was investigated under UV-visible light irradiation at 473 K (Fig. 1).

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The pristine Ga₂O₃ (β -phase, specific surface area (S_a): 9.8 m² g⁻¹) photocatalyst showed the activity in the photo-DRM reaction as previously reported,⁶ although the fixed-bed flow reactor was used in this experiment for the first time. As a result of the screening test, the loading of Pt, Rh, and Ni drastically improved the photocatalytic activity, and the Ni/Ga₂O₃ photocatalyst showed the highest CO and H₂ formation rates. The formation rate of CO was higher than that of H₂ in many cases including the Ni/Ga₂O₃ photocatalyst, which will be discussed later.

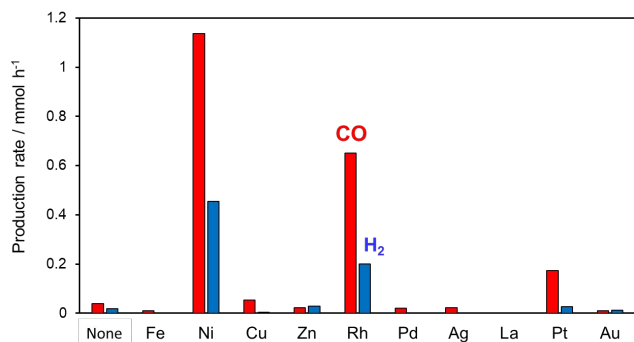


Figure 1. Production rates of CO and H₂ in the photo-DRM reaction over various M/Ga₂O₃ (M: metal) at 473 K. Metal loading was 1 wt% as a metal. Before the catalytic activity test, the sample was reduced at 623 K under H₂ (10%)/Ar gas. CO₂/CH₄/Ar = 1/1/8. Total flow rate: 20 mL min⁻¹. A 300 W Xe lamp was used without any optical filter.

Next, we carried out the activity test of Ni/Ga₂O₃, Ni/Al₂O₃ (γ -phase, S_a : 170 m² g⁻¹) and Ni/TiO₂ (anatase, S_a : 300 m² g⁻¹) with various Ni loadings. Under UV-visible light irradiation, CO and H₂ were effectively formed when the Ni loading is over 1 wt% in Ni/Ga₂O₃, 5 wt% in Ni/Al₂O₃ and 20 wt% in Ni/TiO₂ as shown in Fig. 2. The band gap of Al₂O₃ (7.6 eV, 160 nm)¹⁸ is larger than the energy of the light used in this experiment ($\lambda > 200$ nm), which means that the band-gap excitation of the metal oxide is not necessary in the photo-DRM reaction over the supported Ni catalysts. Among the photocatalysts investigated, the highest formation rates of CO and H₂ were obtained in the 5 wt% Ni/Al₂O₃ catalyst.

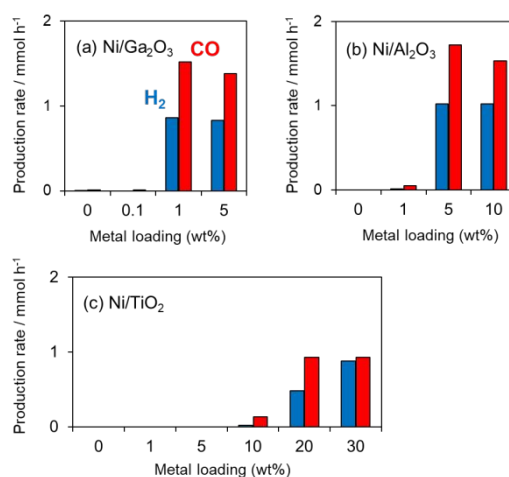


Figure 2. Effect of Ni loading on the activity in the photo-DRM reaction on Ni/Ga₂O₃, Ni/Al₂O₃, and Ni/TiO₂ under UV-visible light irradiation without any optical filter at 473 K. Before the catalytic activity test, the sample was reduced at 623 K under H₂ (10%)/Ar gas. CO₂/CH₄/Ar = 1/1/8. Total flow rate: 20 mL min⁻¹.

To clarify the role of Ni, the effective wavelength of light for the photo-DRM reaction was investigated in the 5 wt% Ni/Al₂O₃ photocatalyst after the H₂ pretreatment at 623 K (Table 1, entries 1 and 2). As a result, the reaction proceeded efficiently even under visible light although the reaction rate decreased to some extent compared with the result under UV-visible light irradiation. The conversions of CO₂ and CH₄ were 21% and 20%, respectively, under visible light. In the dark condition, the reaction did not proceed (entry 3), indicating the reaction is significantly accelerated by visible light at 473 K. The activity was further improved at 573 K under visible light (entries 2, and 4) although the CO and H₂ formation was confirmed in the dark at this temperature (entry 5). Besides pristine Al₂O₃ did not show the activity under visible light, indicating Ni is the active site in the photo-DRM reaction (entry 6).

Effect of the temperature of the H₂ reduction pretreatment was investigated (entries 2, 7–10). When the reduction temperature is below 473 K, no product was observed even under visible light. UV-vis spectroscopy elucidated the broad absorption band around 400–800 nm increased with the reduction temperatures

Table 1. Results of the activity test under various reaction conditions ^a

Entry	Cat. ^b	T_{Red} ^c	Light ^d	T ^e	r^f / mmol h ⁻¹		Conv. ^g (%)		C.B. ^h (%)
					CO	H ₂	CO ₂	CH ₄	
1	Ni/Al ₂ O ₃	623	UV+vis.	473	2.58	1.73	29.4	26.7	95
2	Ni/Al ₂ O ₃	623	vis.	473	1.87	1.20	21.0	19.5	97
3	Ni/Al ₂ O ₃	623	dark	473	n.d. ⁱ	n.d. ⁱ	0	0	100
4	Ni/Al ₂ O ₃	623	vis.	573	3.22	2.21	40.3	33.7	91
5	Ni/Al ₂ O ₃	623	dark	573	1.13	0.64	13.9	11.7	98
6	Al ₂ O ₃	623	vis.	473	n.d. ⁱ	n.d. ⁱ	0	0	100
7	Ni/Al ₂ O ₃	323	vis.	473	n.d. ⁱ	n.d. ⁱ	0	0	100
8	Ni/Al ₂ O ₃	473	vis.	473	n.d. ⁱ	n.d. ⁱ	0	0	100
9	Ni/Al ₂ O ₃	873	vis.	473	1.48	0.90	16.3	14.4	98
10	Ni/Al ₂ O ₃	1073	vis.	473	1.50	1.08	18.0	17.2	96

^a Reaction gas: CO₂/CH₄/Ar=1/1/8, total flow rate: 20 mL min⁻¹. ^b Metal loading: 5 wt% (if present). ^c Temperature of the H₂ pretreatment, ^d Light source: a 300 W Xe lamp, UV+vis.: $\lambda > 200$ nm, vis.: $\lambda > 430$ nm (a long-pass filter was used, Fig. S1), dark: without irradiation. ^e Reaction temperature. ^f Formation rates of CO and H₂. ^g Conversion of X (%) = $([X]_{\text{in}} - [X]_{\text{out}}) / [X]_{\text{in}} \times 100$ (X = CO₂ or CH₄). ^h Carbon balance (eq. 2). ⁱ Not detected.

higher than 623 K (Fig. 3a), possibly due to the formation of metallic Ni species. In addition, XAFS spectroscopy confirmed that the Ni species was partially reduced with the H₂ treatment above 623 K (Fig. 3b), although the XRD pattern did not change for the sample reduced at 623 K (Fig. S3). Thus, the spectroscopic results indicated that the small part of the Ni²⁺ species was reduced into metallic Ni species after the H₂ pretreatment at 623 K. The reduction temperature coincides with previous studies using temperature programmed reduction (TPR) in Ni/Al₂O₃ samples.^{19,20} Combined with the results of the activity tests, it is noticed that the metallic Ni species is responsible for the formation of CO and H₂ under visible light irradiation. In literature,¹⁰ it was proposed that the photo-DRM reaction with Ni catalysts can be accelerated by LSPR effect, where the LSPR effect was confirmed only at relatively high temperature (> 823 K). In our reaction system, the plasmonic excitation of Ni metal species would be essential for the photo-DRM reaction. Besides, the production rates of CO and H₂ increased with the light intensity (*I*) superlinearly (i.e., rate ∝ *I*^{*n*}, *n* > 1, Fig. S2), suggesting that the role of the light is not only local heating via non-radiative plasmonic decay.²¹ Moreover, surface temperature was measured using a remote proved thermometer, and the temperature was 577 K under visible light irradiation (temperature of the reactor: 473 K). In our reaction result at 573 K in the dark condition (Table 1, Entry 5), the formation rates of CO and H₂ were 1.13 and 0.64 mmol h⁻¹, and these values were less than those under visible light irradiation at 473 K (Table 1, Entry 2).

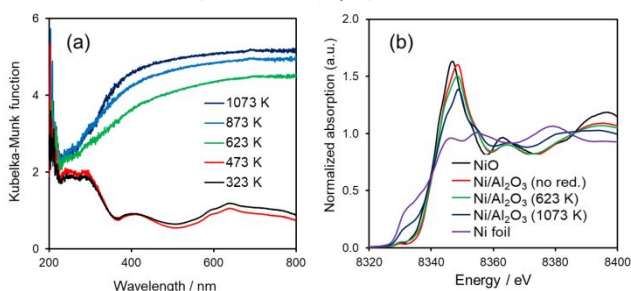


Figure 3. Effect of reduction temperature in the pretreatment on the UV-vis diffuse reflectance spectra (a) and XANES spectra (b) of the Ni/Al₂O₃ sample (Ni loading: 5 wt%).

In the typical DRM reaction using a thermal Ni catalyst, durability of the catalyst is a serious problem since coke formation drastically decreases the catalytic activity.^{22,23} To test the durability of the plasmonic Ni/Al₂O₃ photocatalyst, the activity test was carried out for 100 h (Fig. 4). Although the activity decreased to some extent, it became rather constant after 80 h, and the reaction continuously proceeded even after 100 h. Furthermore, the calculated TON was 280 based on the amount of Ni atoms in the catalysts after 100 h, indicating the reaction proceeds photocatalytically. To investigate the deactivation, we performed several characterizations of the Ni/Al₂O₃ photocatalyst after the reaction for 100 h. X-ray diffraction (XRD) revealed that carbon deposition and formation and/or aggregation of metallic Ni species occurred after the reaction (Fig. S4) although such a carbon species cannot be observed by TEM (Fig. S5). Besides, the content of carbon was estimated to be 3.8 wt% using thermogravimetry (TG) analysis

(Fig. S6), and the value was relatively low compared with typical Ni/Al₂O₃ in thermal DRM reaction although it significantly depends on the reaction condition and catalyst properties. Besides, the carbon balance was calculated using eq. 2,

$$\text{Carbon balance (\%)} = \frac{[\text{CO}_2]_{\text{out}} + [\text{CH}_4]_{\text{out}} + [\text{CO}]_{\text{out}}}{[\text{CO}_2]_{\text{in}} + [\text{CH}_4]_{\text{in}}} \times 100 \quad \text{eq.2}$$

where [X]_{in} and [X]_{out} are partial pressures of X in inlet and outlet gas mixtures, respectively. The carbon balance is almost 100% during the reaction as shown in Fig. 4, which is consistent with the low carbon deposition amount.

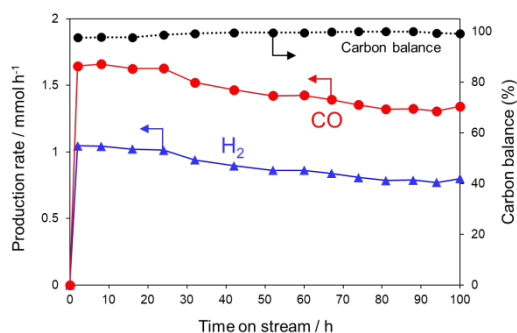


Figure 4. Long-time photo-DRM reaction under visible light on the Ni/Al₂O₃ catalyst. Ni loading: 5wt%. CO₂/CH₄/Ar = 1/1/8. Total flow rate: 20 mL min⁻¹.

Next, we investigated the effect of the partial pressures of CO₂ and CH₄ (*P*_{CO₂} and *P*_{CH₄}) on the formation rates. When *P*_{CO₂} increased from 0.05 to 0.9 atm, the CO formation rate increased monotonically up to 2.7 times and the H₂ formation rate did not change significantly (Fig. 5a). Whereas, increment of *P*_{CH₄} improved the formation rates of both CO and H₂ (Fig. 5b) up to 0.5 atm. In the condition of *P*_{CO₂} < *P*_{CH₄}, the photocatalytic activity markedly decreased with the reaction time (Fig. S8). This indicates that high *P*_{CO₂}/*P*_{CH₄} ratio in the feed gas is important for the stable photocatalytic DRM reaction.

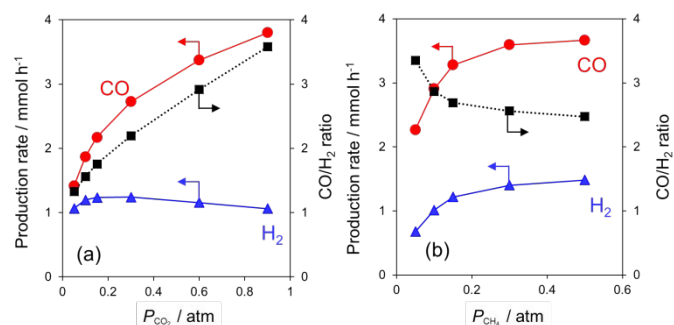
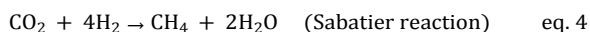


Figure 5. Effect of partial pressures of CO₂ (a) and CH₄ (b) on the formation rates and CO/H₂ ratio in the photo-DRM reaction at 473 K over the 5wt% Ni/Al₂O₃ photocatalysts. Total flow rate: 20 mL min⁻¹, *P*_{CH₄}: 0.1 atm in (a), *P*_{CO₂}: 0.5 atm in (b).

As shown in Fig. 5, the CO/H₂ ratio increased with increasing *P*_{CO₂}, and decreased with increasing *P*_{CH₄}. In addition, the CO formation rate is higher than that of H₂ formation rate in all the reaction conditions in Figs. 4 and 5 although the CO/H₂ ratio is unity in the reaction equation of DRM as shown in eq. 1. In a thermal DRM catalyst, the simultaneous occurrence of reverse water gas shift (RWGS) (eq. 3) reaction results in an increase of

the CO/H₂ ratio over 1.² Thus, we investigated the possibility of hydrogenation of CO₂ over the Ni/Al₂O₃ photocatalyst under visible light irradiation in the reaction condition of H₂/CO₂/Ar = 1/1/8 at a total flow rate of 20 ml min⁻¹. As a result, formation of CO (0.78 mmol h⁻¹) and CH₄ (0.62 mmol h⁻¹) was observed under visible light irradiation, indicating that RWGS (eq. 3) and Sabatier (eq. 4) reactions were promoted over the Ni/Al₂O₃ photocatalyst under visible light irradiation.



In Table 1, CO₂ conversion was higher than that of CH₄ in many cases (Entries 1, 2, 4, 5, 9, and 10), which can be explained by the eqs. 3 and 4. Furthermore, we confirmed the formation of water in the photo-DRM reaction at 473 K under visible light using gas chromatography (Fig. S9). This result supports the simultaneous occurrence of RWGS and Sabatier reactions during the photo-DRM reaction, which results in the high CO/H₂ ratio in these reaction conditions. The selectivity change in the different partial pressure condition can be interpreted by the above reactions. The rate of RWGS reaction would increase with increasing CO₂ pressure, which results in the high CO/H₂ ratio as shown in Fig. 5a. Although further investigation is necessary to explain the change of the CO/H₂ ratio, the results of the partial pressure dependence clearly demonstrated that the CO/H₂ ratio was successfully controlled by just changing CO₂/CH₄ ratio in the feed gas in the present photo-DRM reaction system.

Conclusions

A plasmonic Ni photocatalyst supported on Al₂O₃ showed the high activity for the photo-DRM reaction under visible light at a mild temperature of 473 K. The metallic Ni species is essential for the high activity to produce CO and H₂, which supported the LSPR mechanism for the improvement of the catalytic activity. The CO/H₂ ratio in the product gas can be controlled by just changing CO₂/CH₄ ratio in the feed gas mixture.

Conflicts of interest

There are no conflicts to declare.

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Table of Content

CO₂ reforming with CH₄ proceeded at low temperature (473 K) to form syngas over plasmonic Ni catalysts under visible light

